

Editorial

Acknowledgement to Reviewers of *Crystals* in 2015

Crystals Editorial Office

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The editors of *Crystals* would like to express their sincere gratitude to the following reviewers for assessing manuscripts in 2015.

We greatly appreciate the contribution of expert reviewers, which is crucial to the journal's editorial decision-making process. Several steps have been taken in 2015 to thank and acknowledge reviewers. Good, timely reviews are rewarded with a discount off their next MDPI publication. By creating an account on the submission system, reviewers can access details of their past reviews, see the comments of other reviewers, and download a letter of acknowledgement for their records. In addition, MDPI has launched a collaboration with Publons, a website that seeks to publicly acknowledge reviewers on a per journal basis. This is all done, of course, within the constraints of reviewer confidentiality. Feedback from reviewers shows that most see their task as a voluntary and mostly unseen work in service to the scientific community. We are grateful to our reviewers for the contribution they make.

Albrecht-Schmitt, Thomas	Hwu, Shiou-Jyh	Rosenthal, Anja
Aoki, Katsuyuki	Ignés-Mullol, Jordi	Ruiz, José
Balandin, Alexander A.	Kauzlarich, Susan	Hosmane, Narayan S.
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Barone, Giampaolo	Kim, Youngmee	Samsonenko, D. G.
Bertolasi, Valerio	Kitazawa, Takafumi	Scheiner, Steve
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Bielenica, Anna	Knight, K. S.	Seidel, Rüdiger W.
Binions, Russell	Kobayashi, Shunsuke	Senyuk, Bohdan
Brantley, William A.	Kolmogorov, Alexey	Seriani, Nicola
Bučar, Dejan-Krešimir	Kukla, Maija	Shao, Xiangfeng
Bulychev, Valentin P.	Laha, Kinkar	Shenderovich, Ilya G.
Cardellicchio, Cosimo	Lang, Fengqun	Sherbow, Tobias J.
Casañ-Pastor, N.	Lapidus, Saul	Shih, Shao-Ju
Chen, Jia	Lavrentovich, Oleg D.	Shultz, David A.
Chen, Swe-Kai	Lee, Wei	Siping, Pang
Cinca, N.	Lee, Hyuck Mo	Sluiter, Marcel
Cossairt, Brandi M.	Lemaire, Martin T.	Solokha, Pavlo
Costa, Maria-margarida R. R.	Lewis, William	Solovyev, I. V.
Cramer, Roger E.	Li, Mingjun	Son, Jong Yeog
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Demirci, Umit B.	Lin, Qisheng	Stannarius, Ralf

Duh, Jenq-Gong	Liu, Shih-yuan	Starikov, Evgeni B.
Dullens, Roel	Łuczak, Justyna	Sunatsuki, Yukinari
Edelmann, Frank	Ma, Yue	Svoboda, Hernán G.
El-Ghoury, Abdelkrim	MacGillivray, Leonard R.	Tappan, Bryce C.
Elder, David P.	Majka, Jarosław	Terenzi, Alessio
Faessler, Thomas	Malathy Sony, S. M.	Tonelli, Alan E.
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Fini, Adamo	Martirosyan, Karen	Tsipis, Athanassios C.
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George, Fytas	Milanese, Chiara	Vangala, Venu
Ghule, Vikas D.	Miyake, Hiroyuki	Velian, Alexandra
Giménez, Carlos	Mokaya, Robert	Vezzu, Dilep
Gomez-Garcia, Carlos Jose	Morozkin, A. V.	Vila, José Manuel
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Gorbitz, Carl Henrik	Naumov, Pance	Wang, Chih-Chieh
Graiff, Claudia	Niewa, Rainer	Wang, Shanfeng
Guo, Hong	Nimesh, Sasidharan	Wannemacher, Reinhold
Halet, Jean François	Olmstead, Marilyn M.	Weinhold, Frank
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Hayakawa, Tohru	Pineda, Eufemio Moreno	Wu, Shin-Tson
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Hovorun, Dmytro M.	Punzo, Francesco	Yu, Zaiqun
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Huo, Fang Jun	Renner, Frank	Zhu, Weihua
Huot, Jacques	Rościszewski, Krzysztof	Zmejkovski, Bojana
Huppertz, Hubert		



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